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Biselx et al.

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(54) **MICROMETER**

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(73) Assignee: **TESA SA**, Renens (CH)

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Related U.S. Patent Documents

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(51) **LOC (11) Cl.** **10-04**
(52) **U.S. Cl.**
USPC **D10/73**
(58) **Field of Classification Search**
USPC D10/73, 74, 79, 80
CPC . G01B 3/20; G01B 3/205; G01B 5/24; G01B 3/18; G01B 3/008
See application file for complete search history.

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(57) **CLAIM**

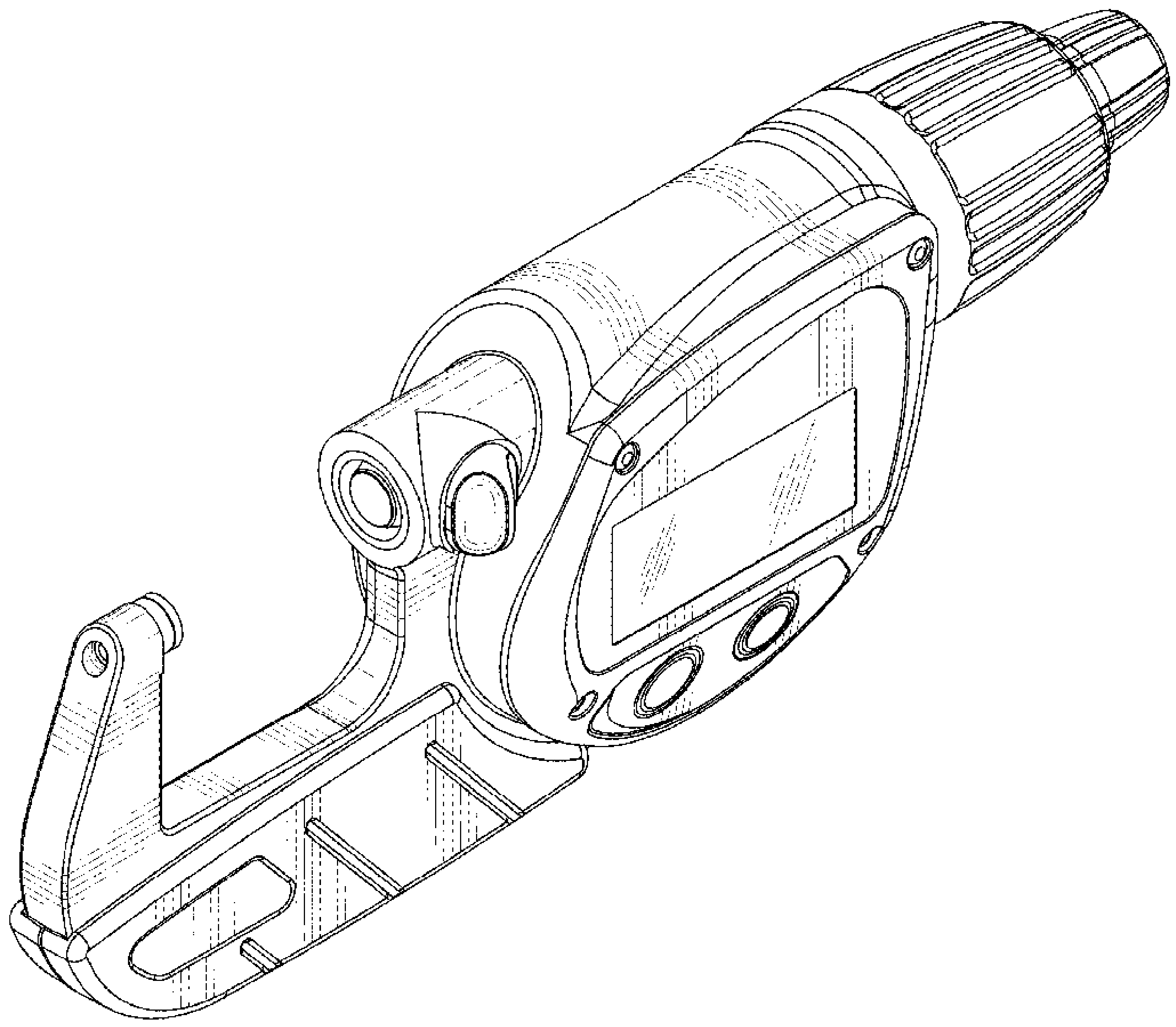
The ornamental design for a micrometer, as shown and described.

DESCRIPTION

[FIG. **1** is an upper perspective view of an exemplary micrometer;]
[FIG. **2** is a front view of the micrometer;]
[FIG. **3** is a rear view of the micrometer;]
[FIG. **4** is a bottom view of the micrometer;]
[FIG. **5** is a top view of the micrometer;]
[FIG. **6** is a left side view of the micrometer;]
[FIG. **7** is a front view of another exemplary micrometer, with the other views the same as shown above in connection with FIG. **1**; and,]
[FIG. **8** is a front view of still another exemplary micrometer, with the other view the same as shown above in connection with FIG. **1**.]
FIG. 9 is a top and front perspective view of a micrometer;
FIG. 10 is a front elevation view of the micrometer;
FIG. 11 is a rear elevation view of the micrometer;
FIG. 12 is a left side elevation view of the micrometer;
FIG. 13 is a top plan view of the micrometer; and,
FIG. 14 is a bottom plan view of the micrometer.

1 Claim, 14 Drawing Sheets

Matter enclosed in heavy brackets [ ] appears in the original patent but forms no part of this reissue; matter printed in italics indicates the additions made by reissue.



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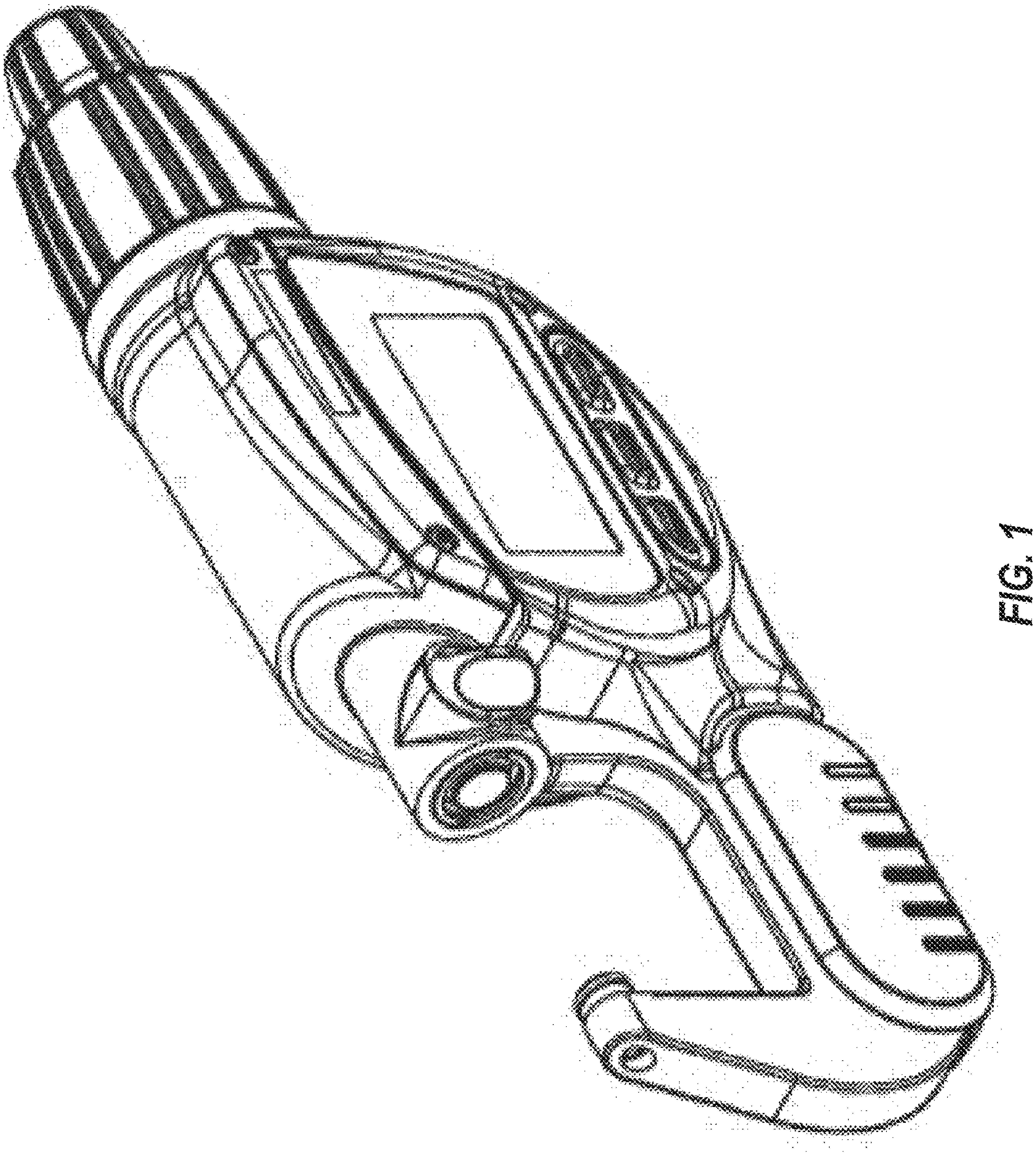

FIG. 1
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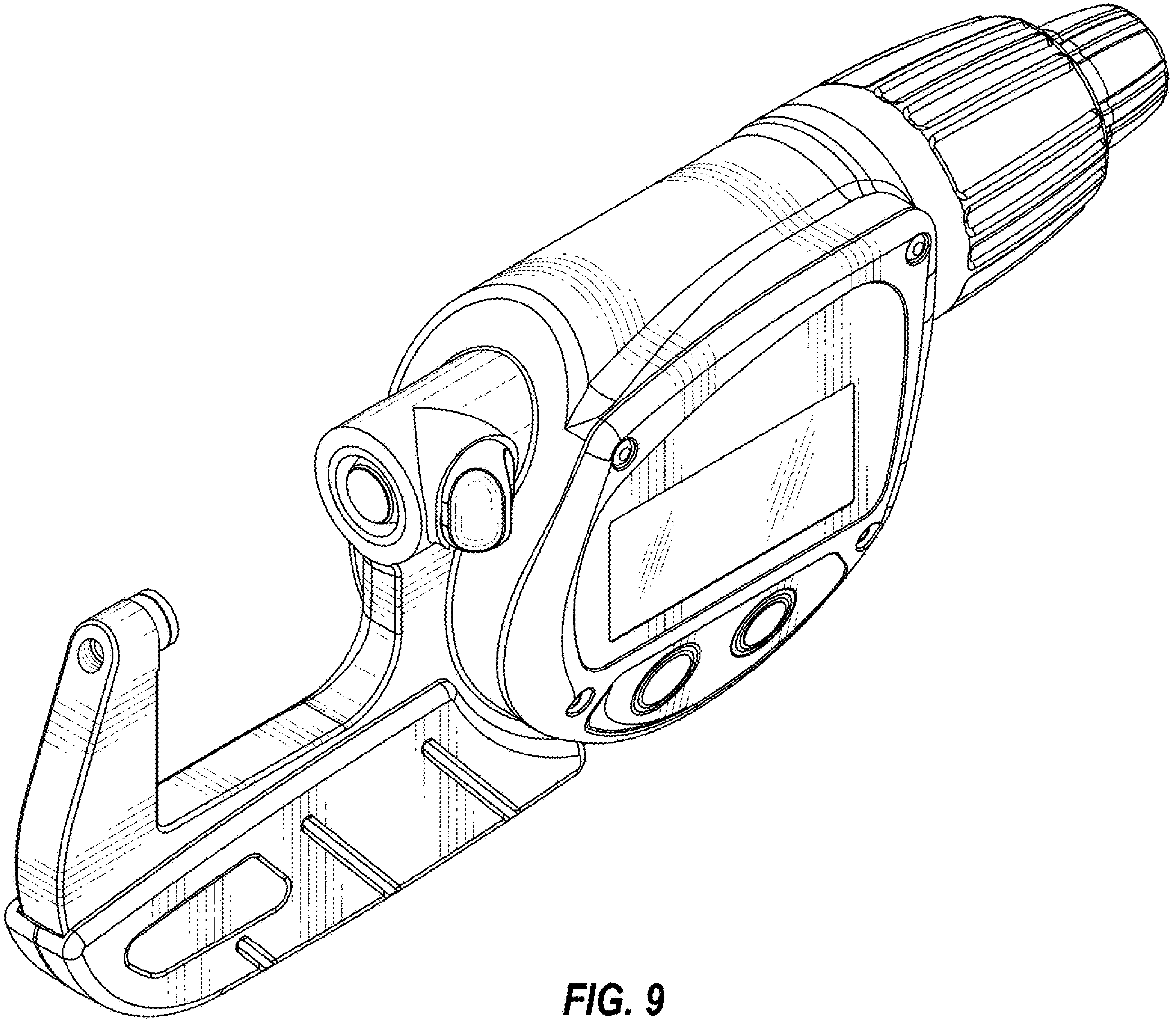

FIG. 9
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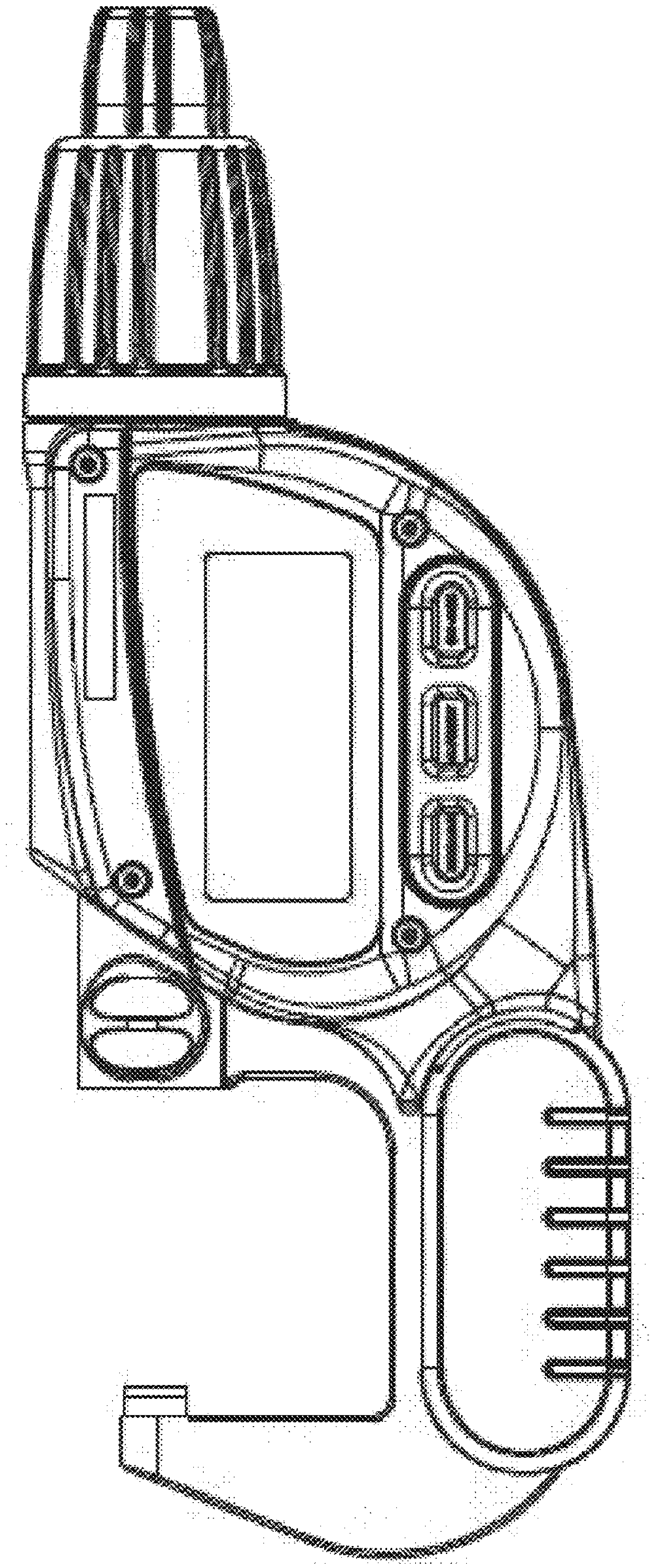

FIG. 2
CANCELED

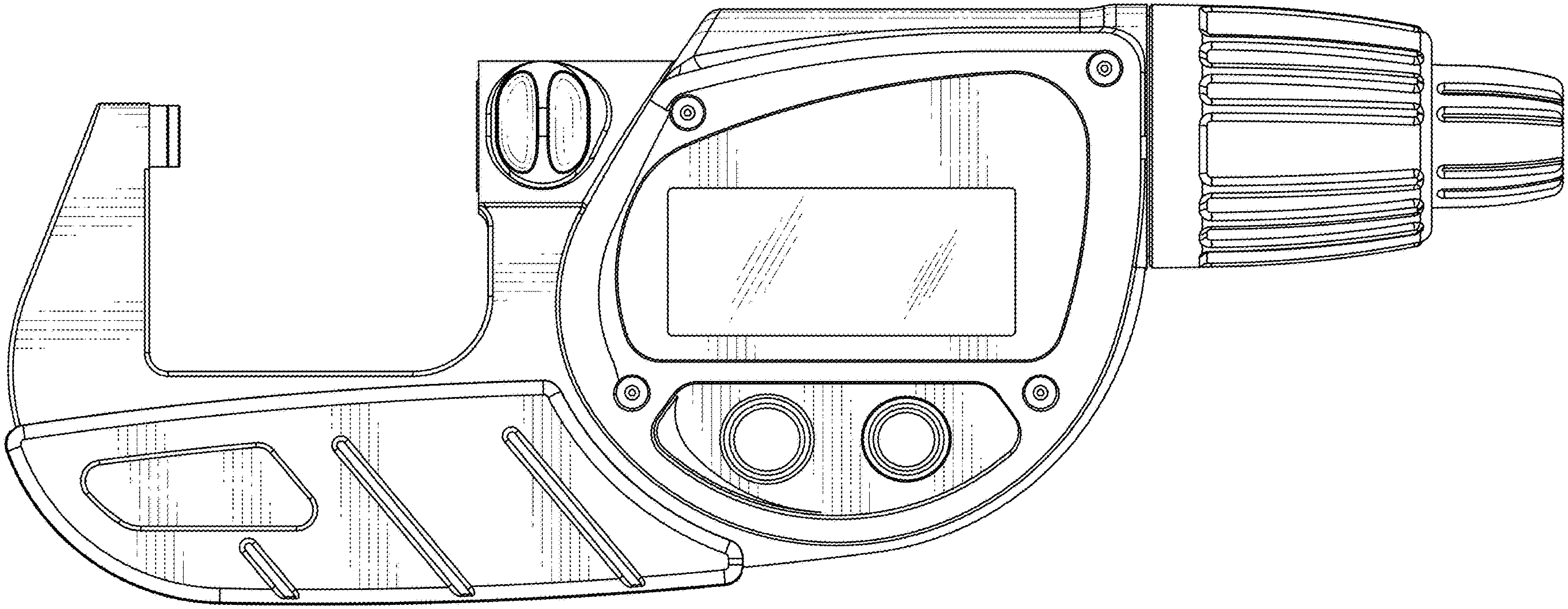

FIG. 10
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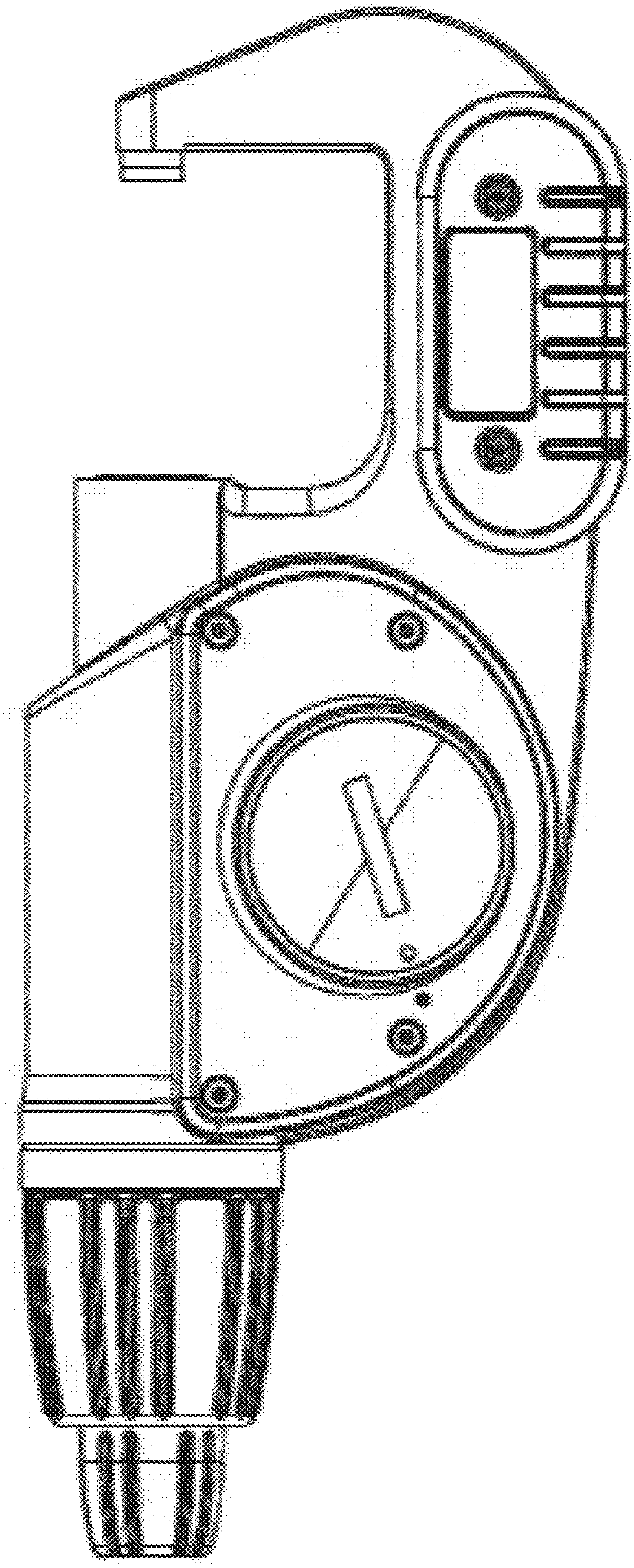

FIG. 3
CANCELED

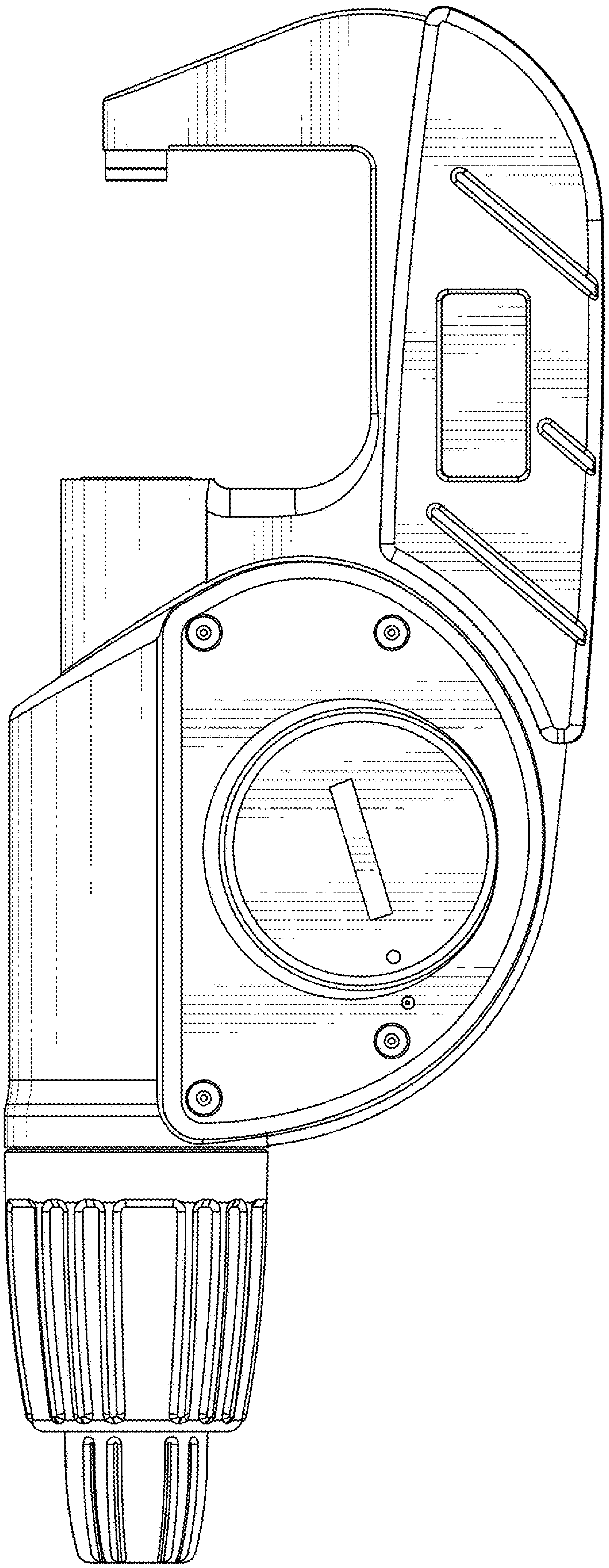

FIG. 11
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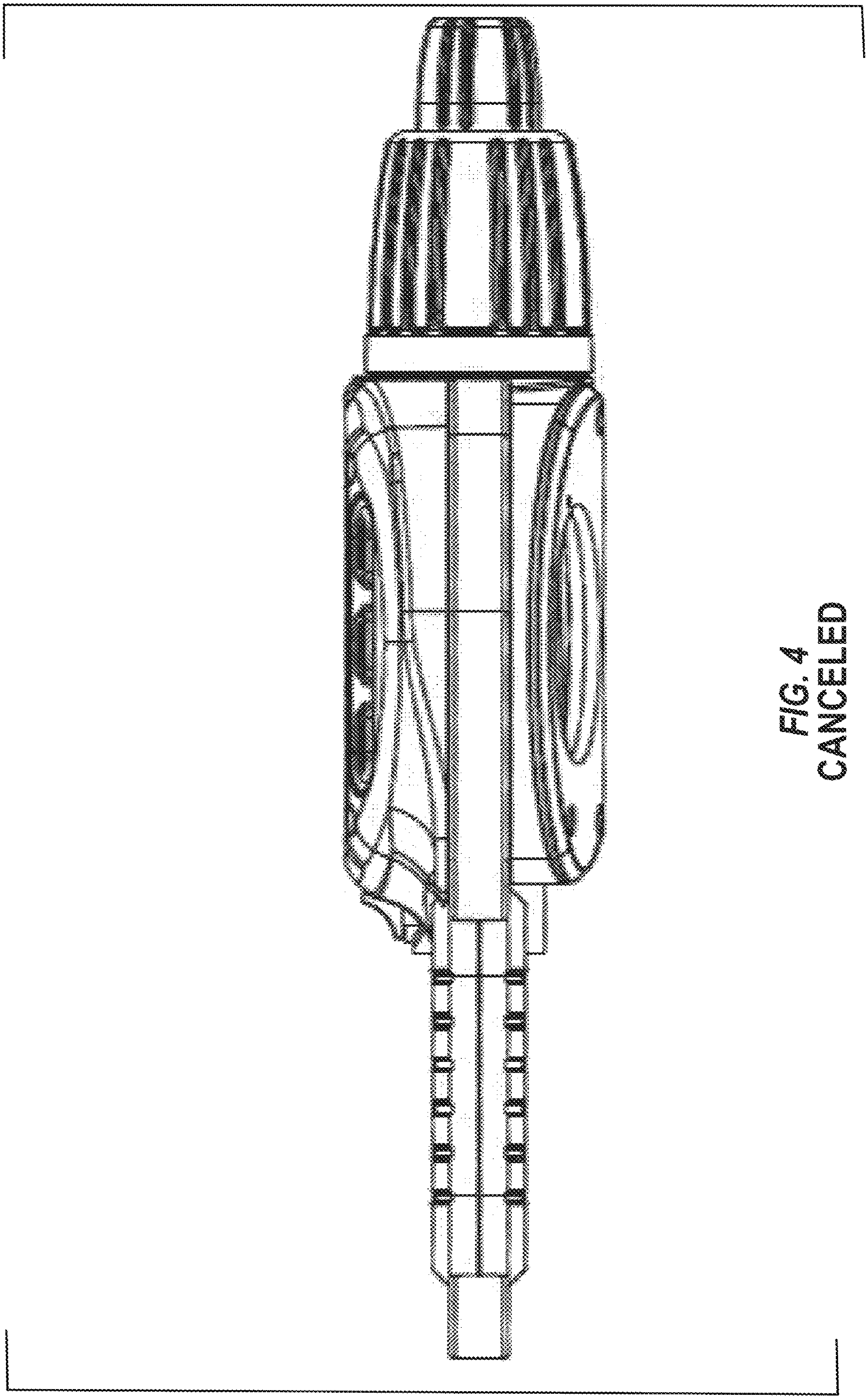

FIG. 4
CANCELED

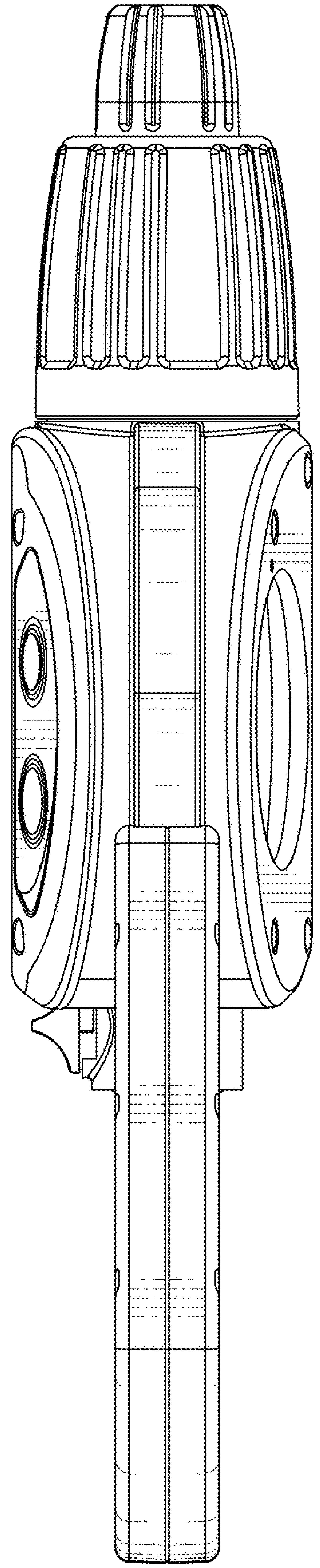

FIG. 12
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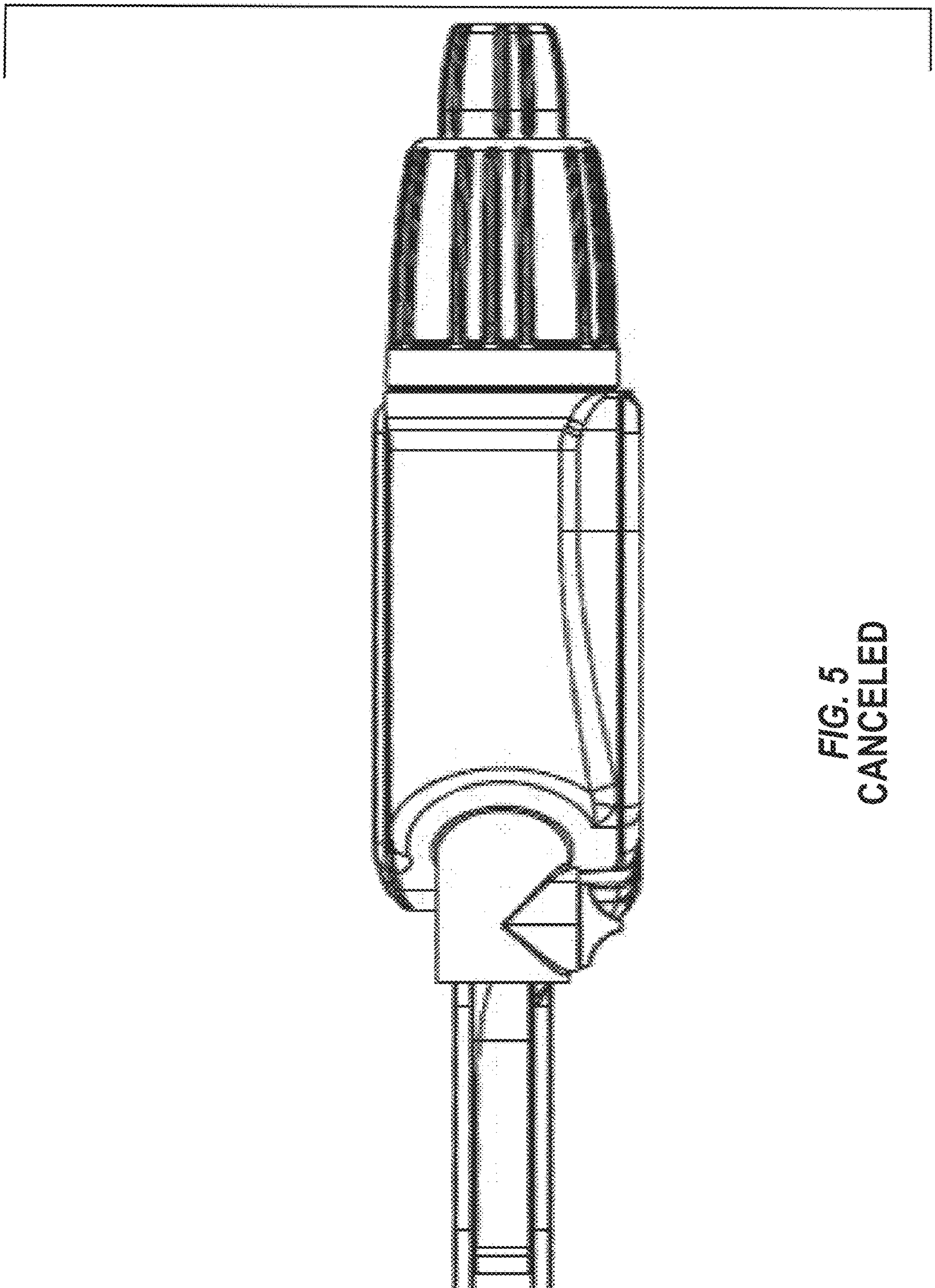

FIG. 5
CANCELED

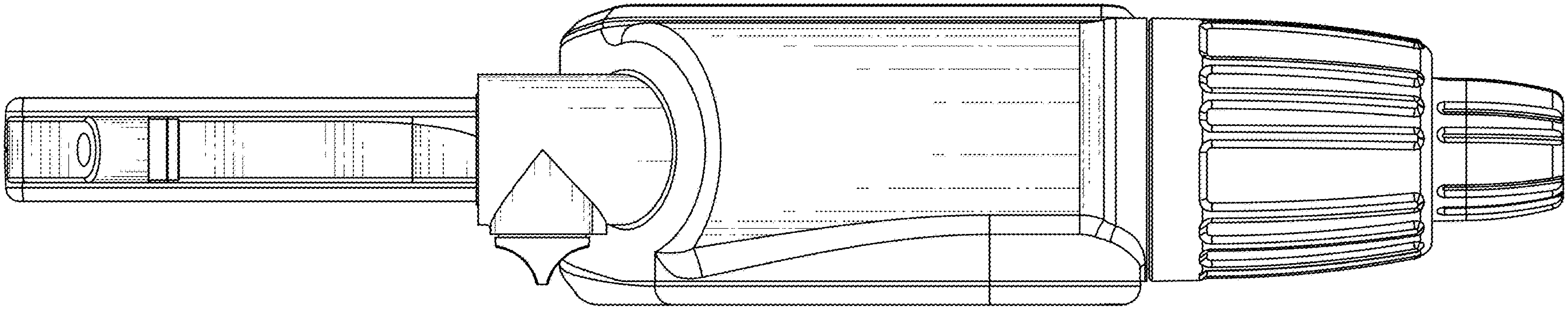

FIG. 13
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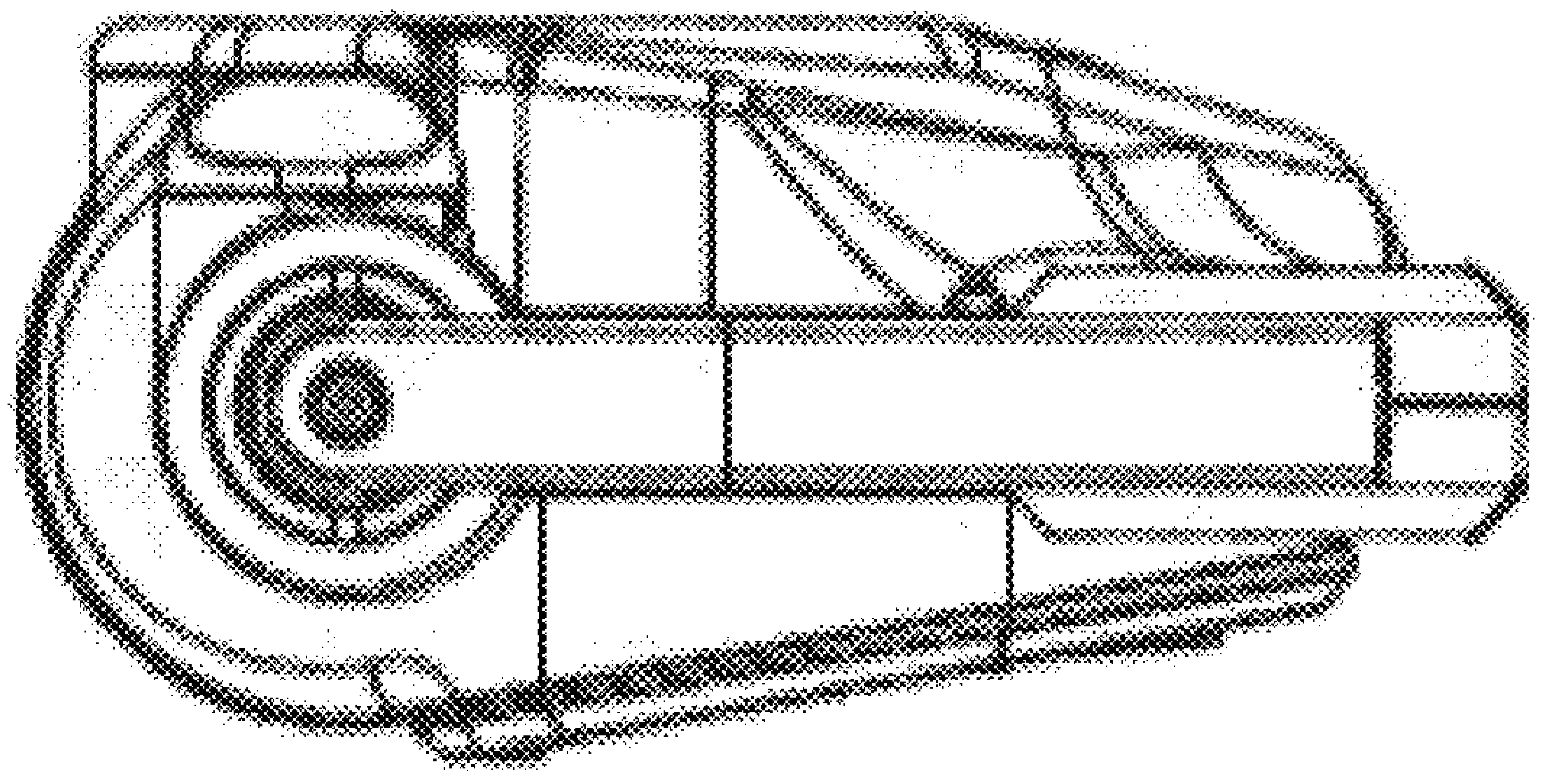

FIG. 6
CANCELED

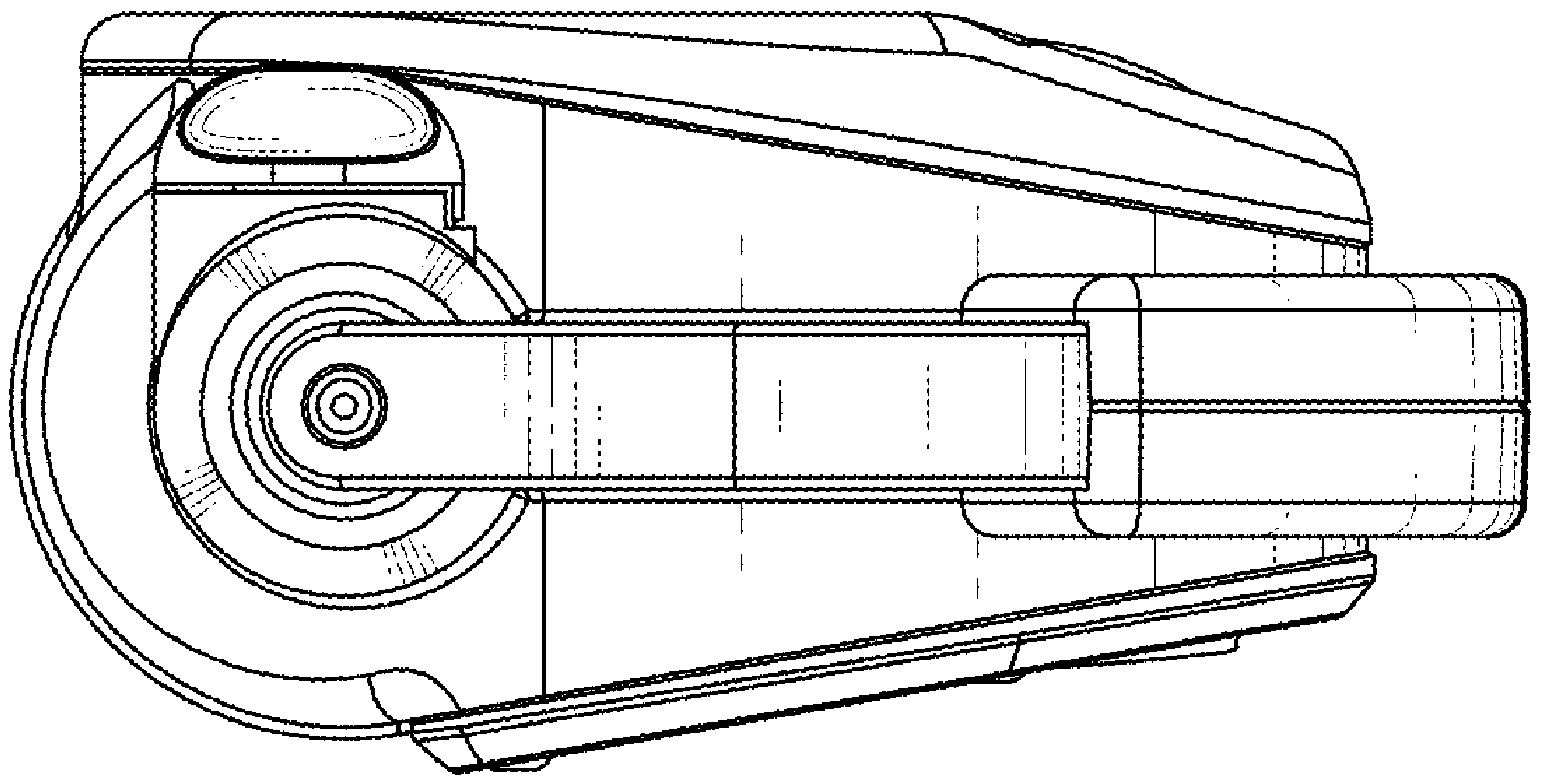

FIG. 14
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FIG. 7
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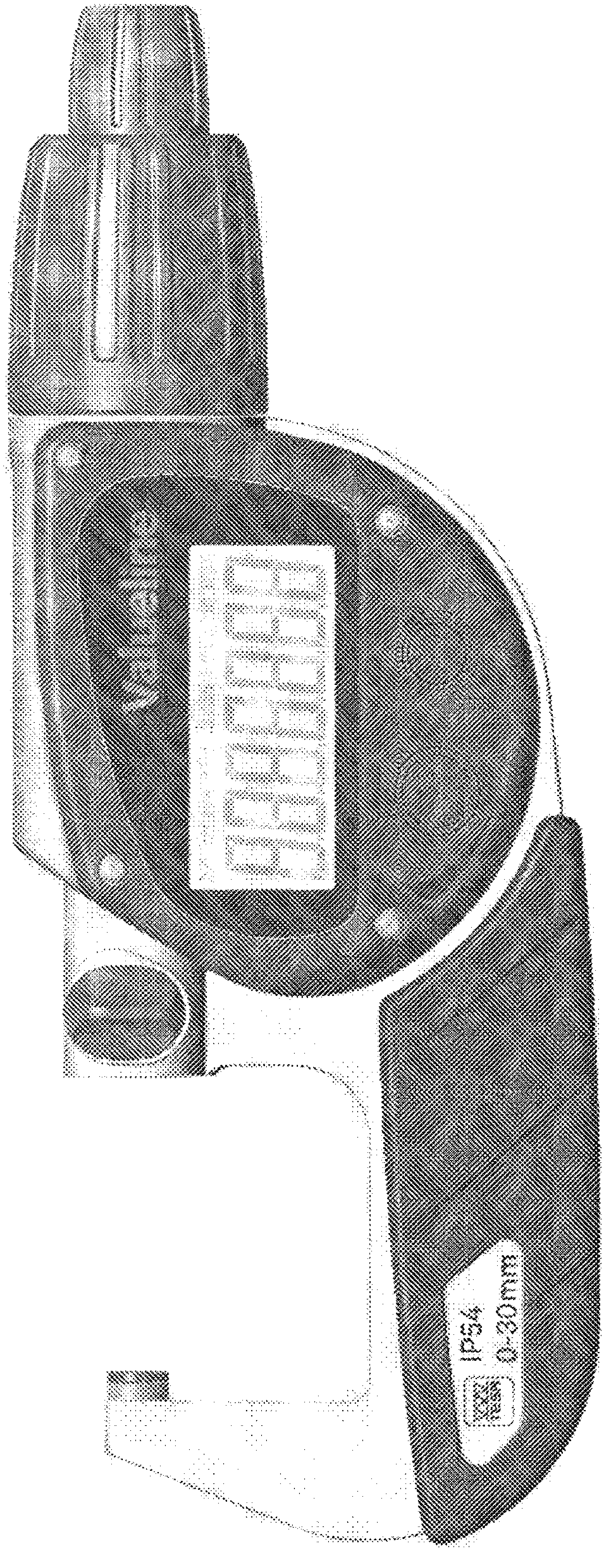

FIG. 8
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